TEMPERATURE CONTROL SYSTEM AND PLASMA PROCESSING SYSTEM

ABSTRACT

The disclosed temperature control system includes a first segment, a second segment, and a connector. The first segment includes a first temperature control circuit and a first case accommodating the first temperature control circuit therein, the first temperature control circuit including a first heat exchanger configured to exchange heat with a first temperature-controlled medium. The second segment includes a first tank and a first pump in a first circulation system configured to circulate the first temperature-controlled medium through a first flow path in a first member of a plasma processing apparatus and includes a second case accommodating the first tank and the first pump therein. The connector is a part of the first circulation system, is disposed between the first segment and the second segment, and is connected between the first pump and the first heat exchanger.

Fig. 3